

Design of $\text{La}_{2-x}\text{Pr}_x\text{NiO}_{4+\delta}$ SOFC cathodes: a compromise in electrochemical performance and thermodynamic stability

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FULLPROF refinements of the XRD patterns of the $\text{La}_{2-x}\text{Pr}_x\text{NiO}_{4+\delta}$ ($x = 0, 0.5$ and 2) films prepared by ESD on a CGO pellet.

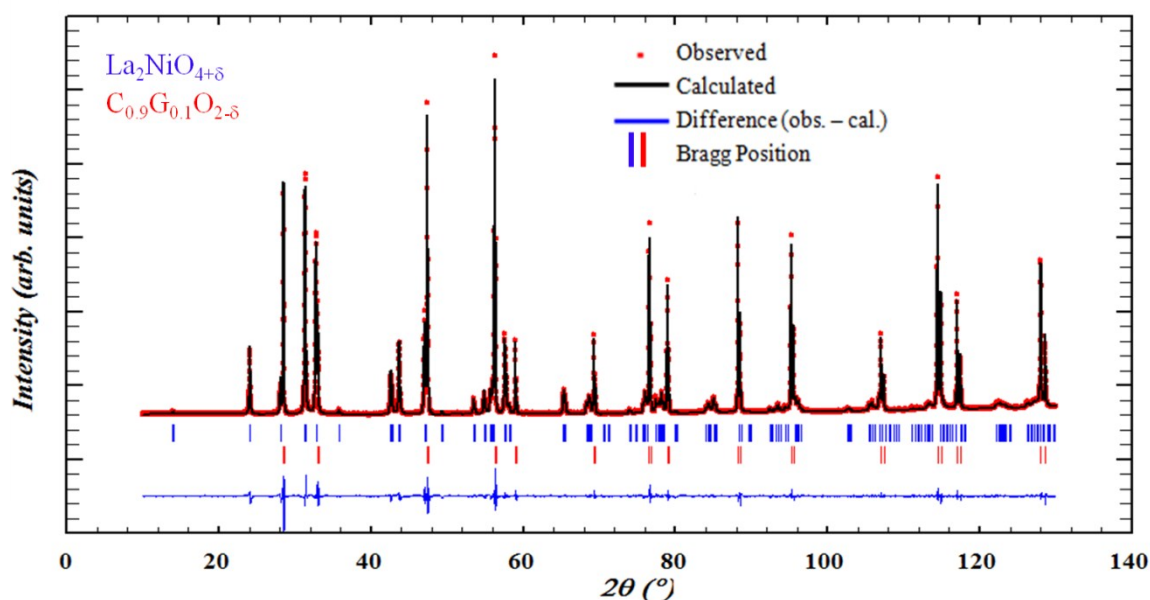


Fig. S1 FULLPROF refinement of the XRD patterns of $\text{La}_2\text{NiO}_{4+\delta}$ film deposited by ESD on a CGO pellet (Fitting parameters: $\chi^2 = 6.99$, Bragg R-factor = 1.22 and RF-factor = 0.752 for $\text{La}_2\text{NiO}_{4+\delta}$; Bragg R-factor = 1.84 and RF-factor = 1.00 for CGO).

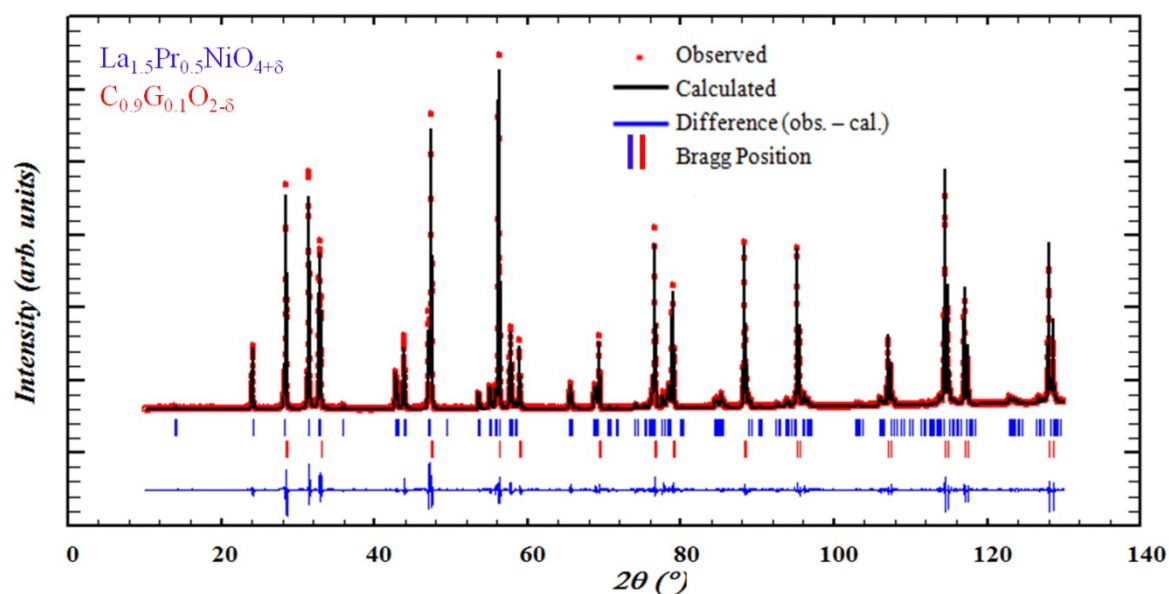


Fig. S2 FULLPROF refinement of the XRD patterns of $\text{La}_{1.5}\text{Pr}_{0.5}\text{NiO}_{4+\delta}$ film deposited by ESD on a CGO pellet (Fit parameters: $\chi^2 = 7.44$, Bragg R-factor = 1.36 and RF-factor = 0.99 for $\text{La}_{1.5}\text{Pr}_{0.5}\text{NiO}_{4+\delta}$; Bragg R-factor = 1.48 and RF-factor = 0.77 for CGO).

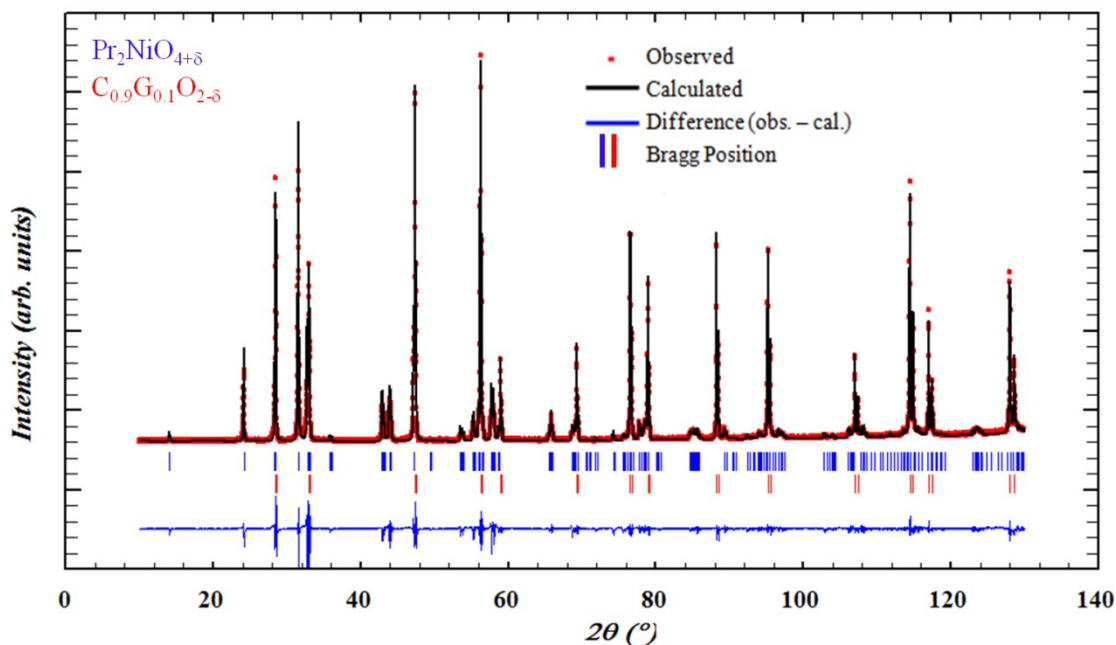


Fig. S3 FULLPROF refinement of the XRD patterns of $\text{Pr}_2\text{NiO}_{4+\delta}$ film deposited by ESD on a CGO pellet (Fit parameters: $\chi^2 = 10.3$, Bragg R-factor = 1.09 and RF-factor = 0.67 for $\text{Pr}_2\text{NiO}_{4+\delta}$; Bragg R-factor = 0.83 and RF-factor = 0.49 for CGO).

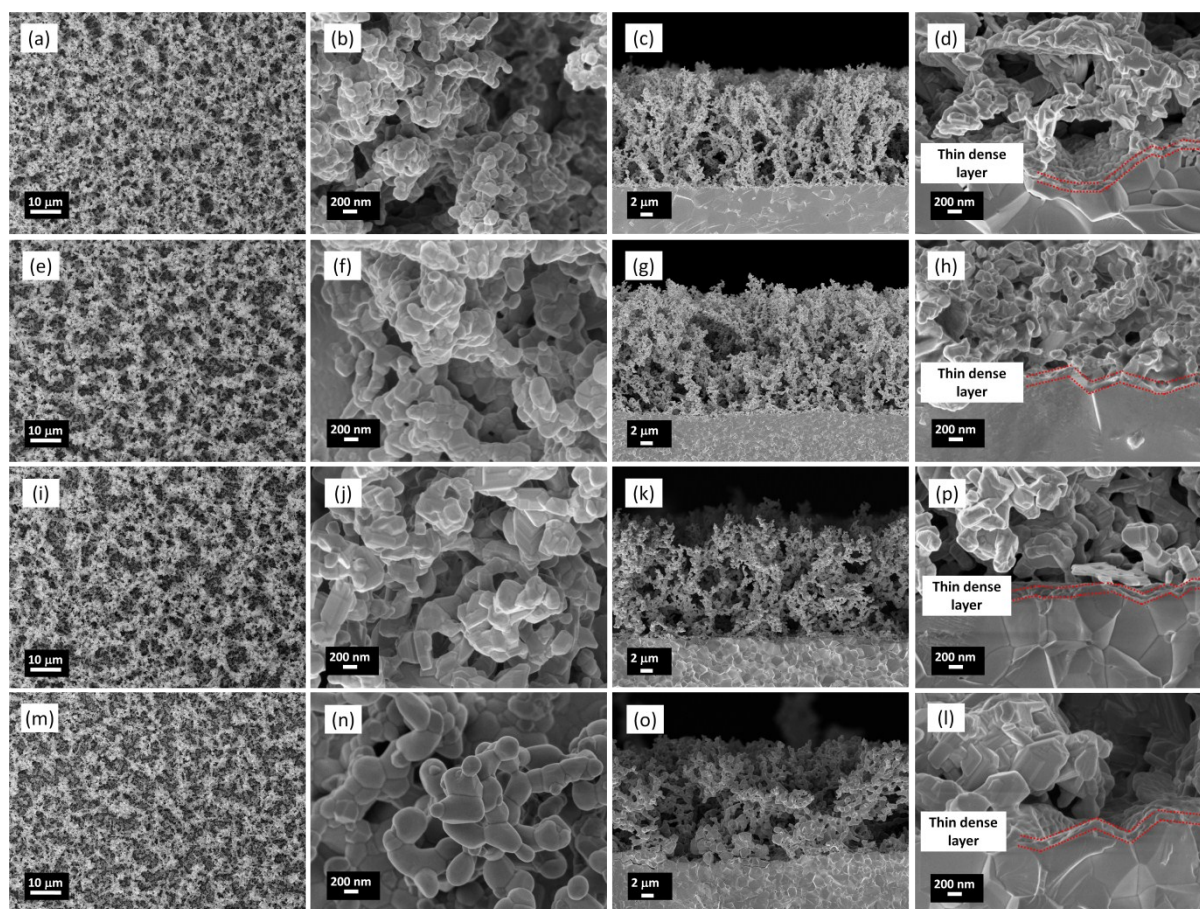


Fig. S4 SEM micrographs of the $\text{La}_{2-x}\text{Pr}_x\text{NiO}_{4+\delta}$ ($0 \leq x \leq 2$) single layer films on a CGO substrate, $\text{La}_2\text{NiO}_{4+\delta}$: (a, b) surface, (c, d) cross section; $\text{La}_{1.5}\text{Pr}_{0.5}\text{NiO}_{4+\delta}$: (e, f) surface, (g, h) cross section; $\text{LaPrNiO}_{4+\delta}$: (i, j) surface, (k, l) cross section and $\text{Pr}_2\text{NiO}_{4+\delta}$: (m, n) surface, (o, p) cross section.

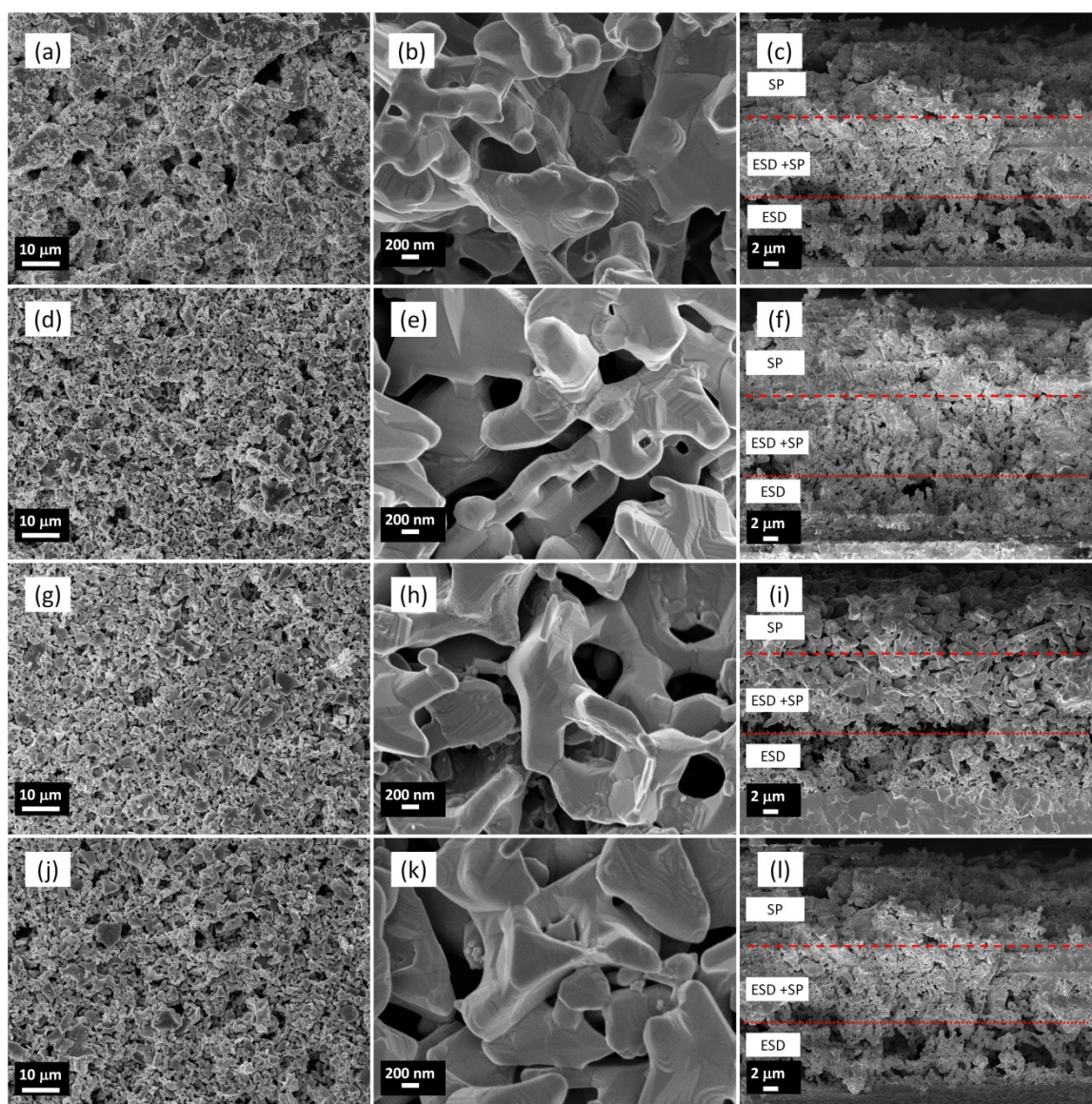


Fig. S5 SEM micrographs of the $\text{La}_{2-x}\text{Pr}_x\text{NiO}_{4+\delta}$ ($0 \leq x \leq 2$) double layer films on a CGO substrate, $\text{La}_2\text{NiO}_{4+\delta}$: (a, b) surface, (c) cross section; $\text{La}_{1.5}\text{Pr}_{0.5}\text{NiO}_{4+\delta}$: (d, e) surface, (f) cross section; $\text{LaPrNiO}_{4+\delta}$: (g, h) surface, (i) cross section and $\text{Pr}_2\text{NiO}_{4+\delta}$: (j, k) surface, (l) cross section.